

FIG.
図 1

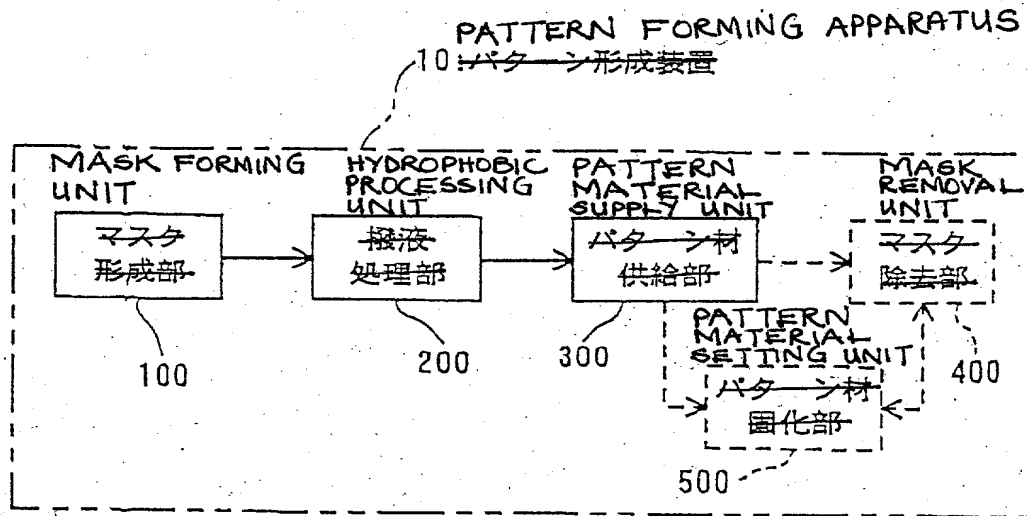


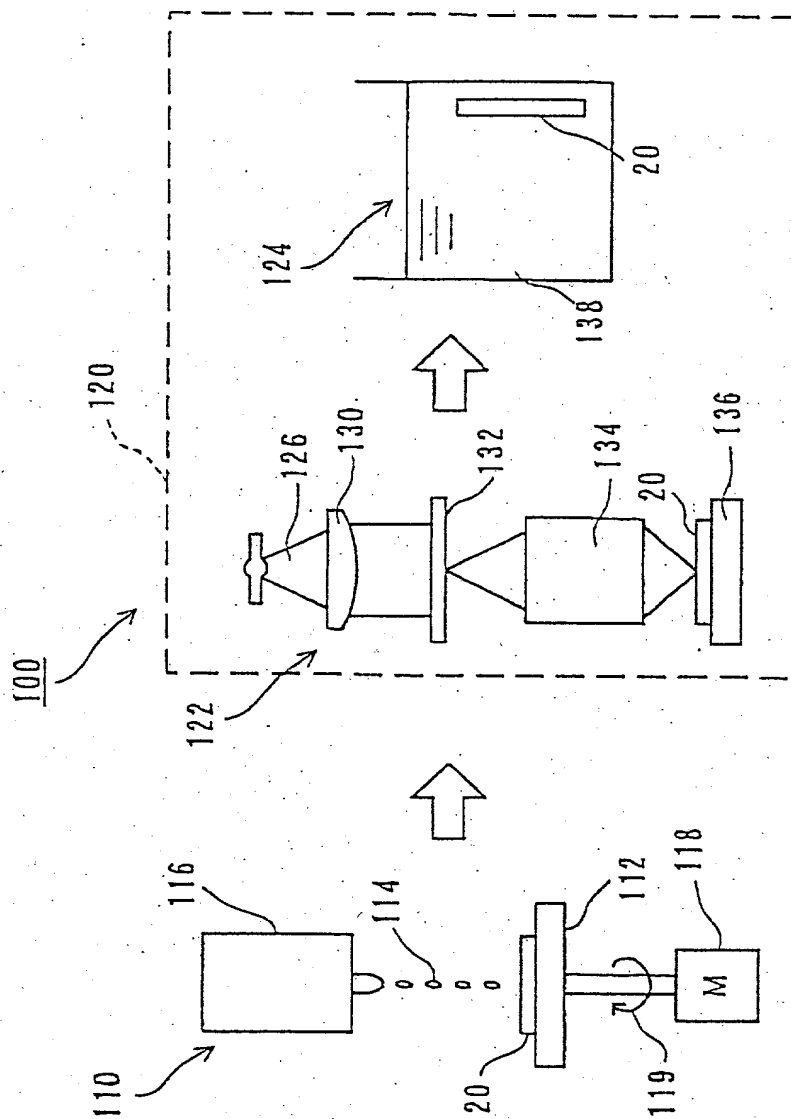
FIG.
2

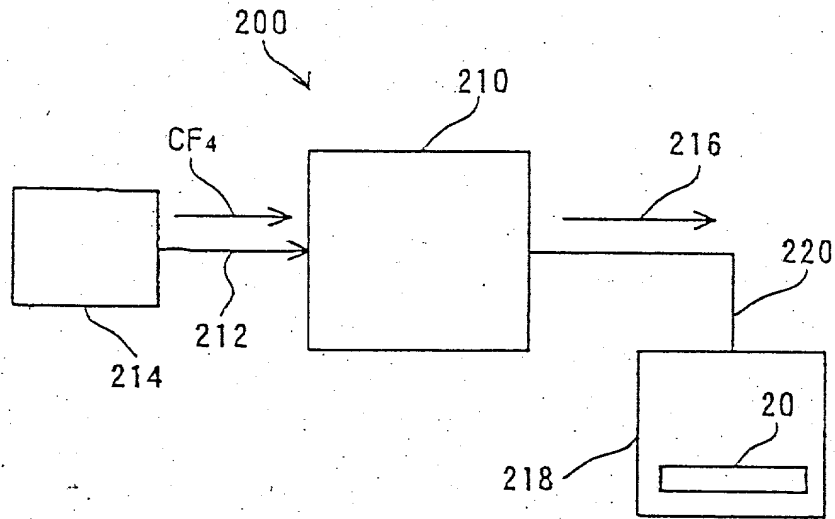
FIG.
~~2~~ 3

FIG.
4

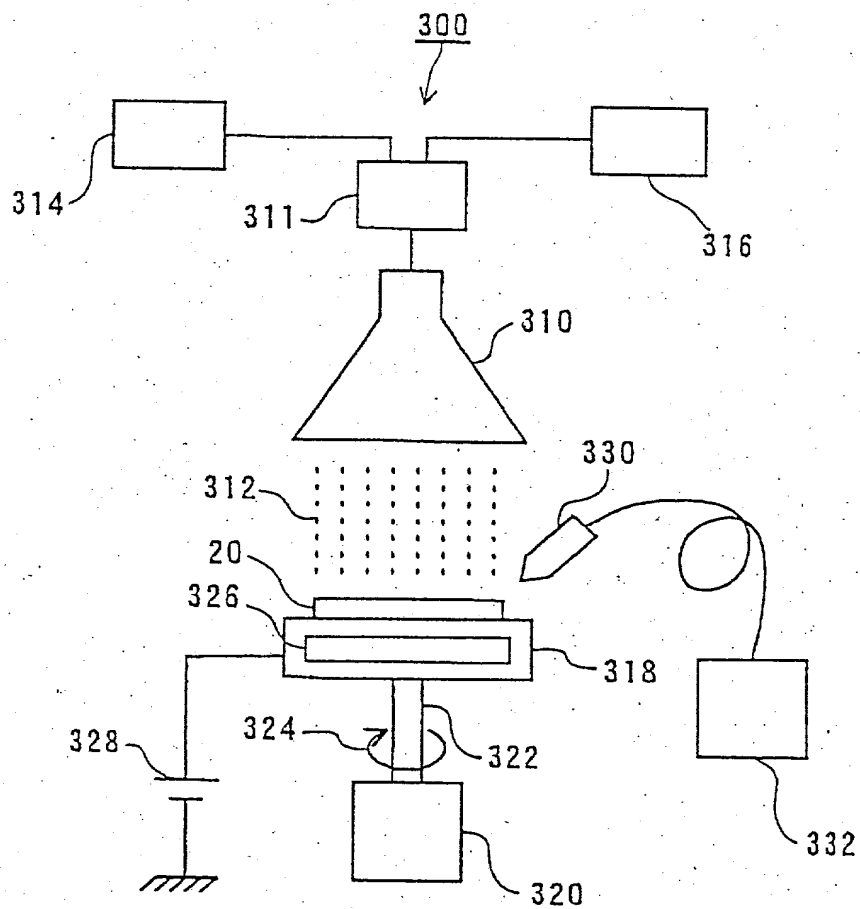


FIG.
図 5

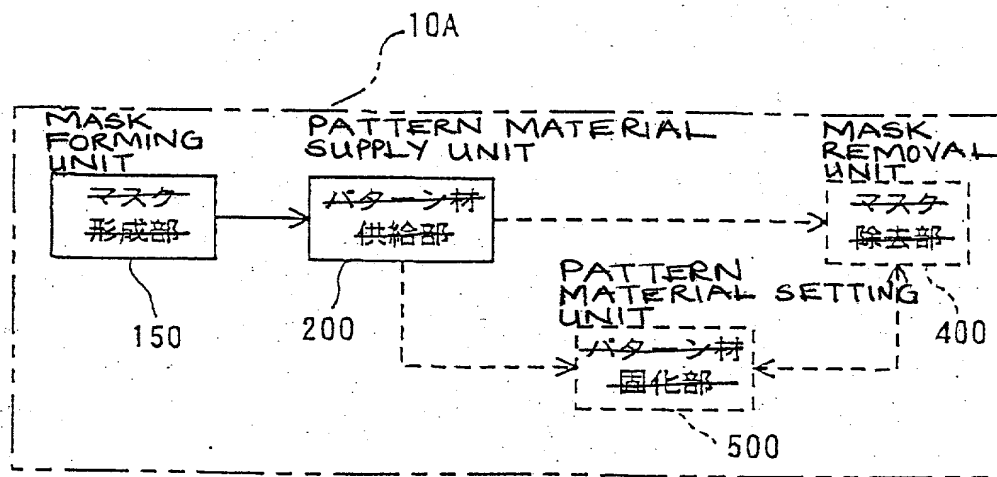


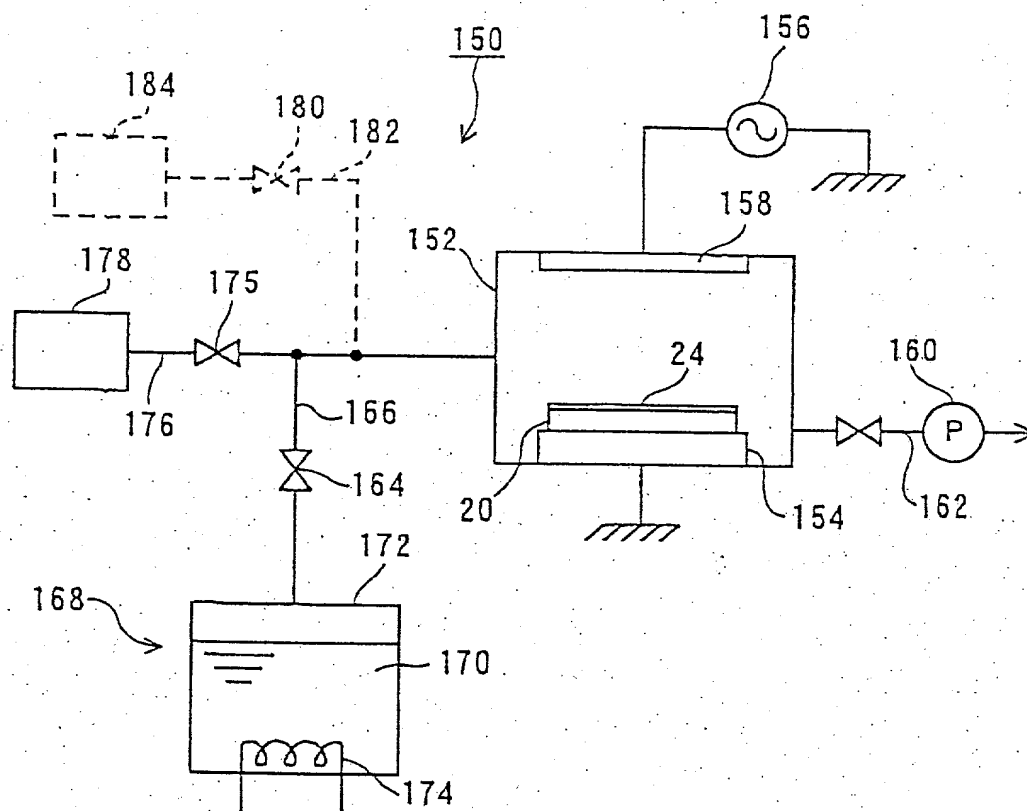
FIG.
6

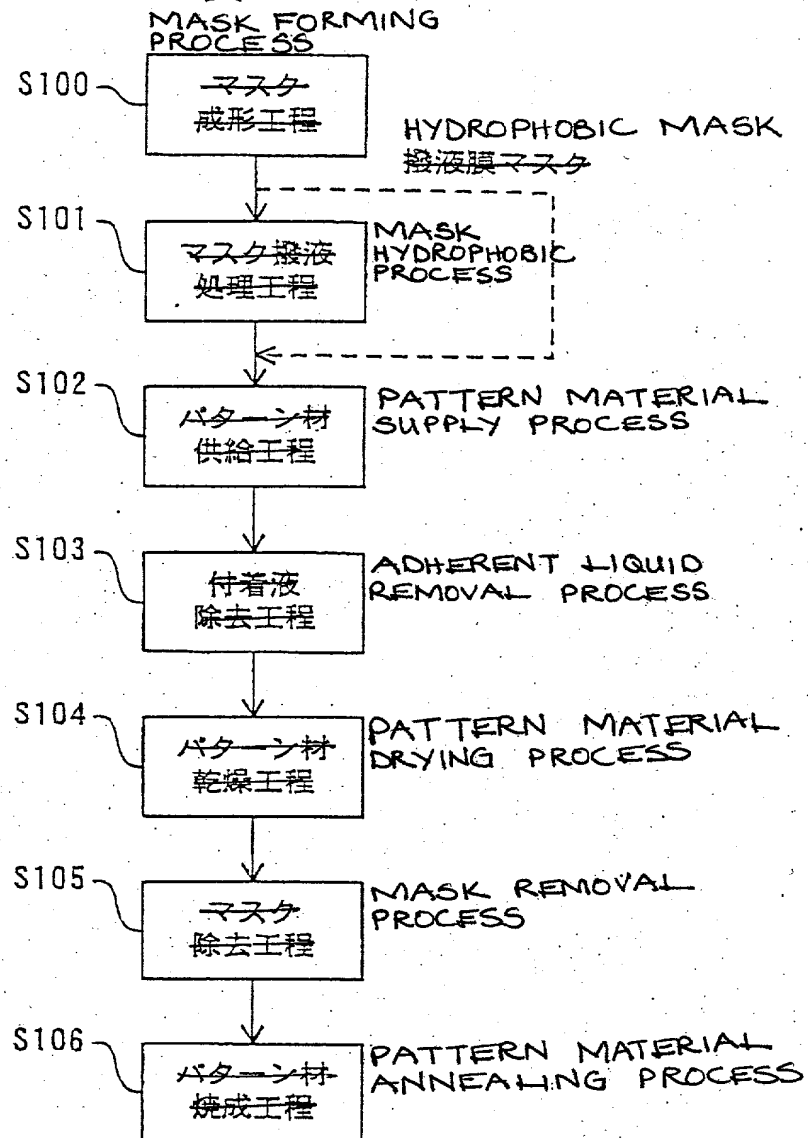
FIG.
図 7

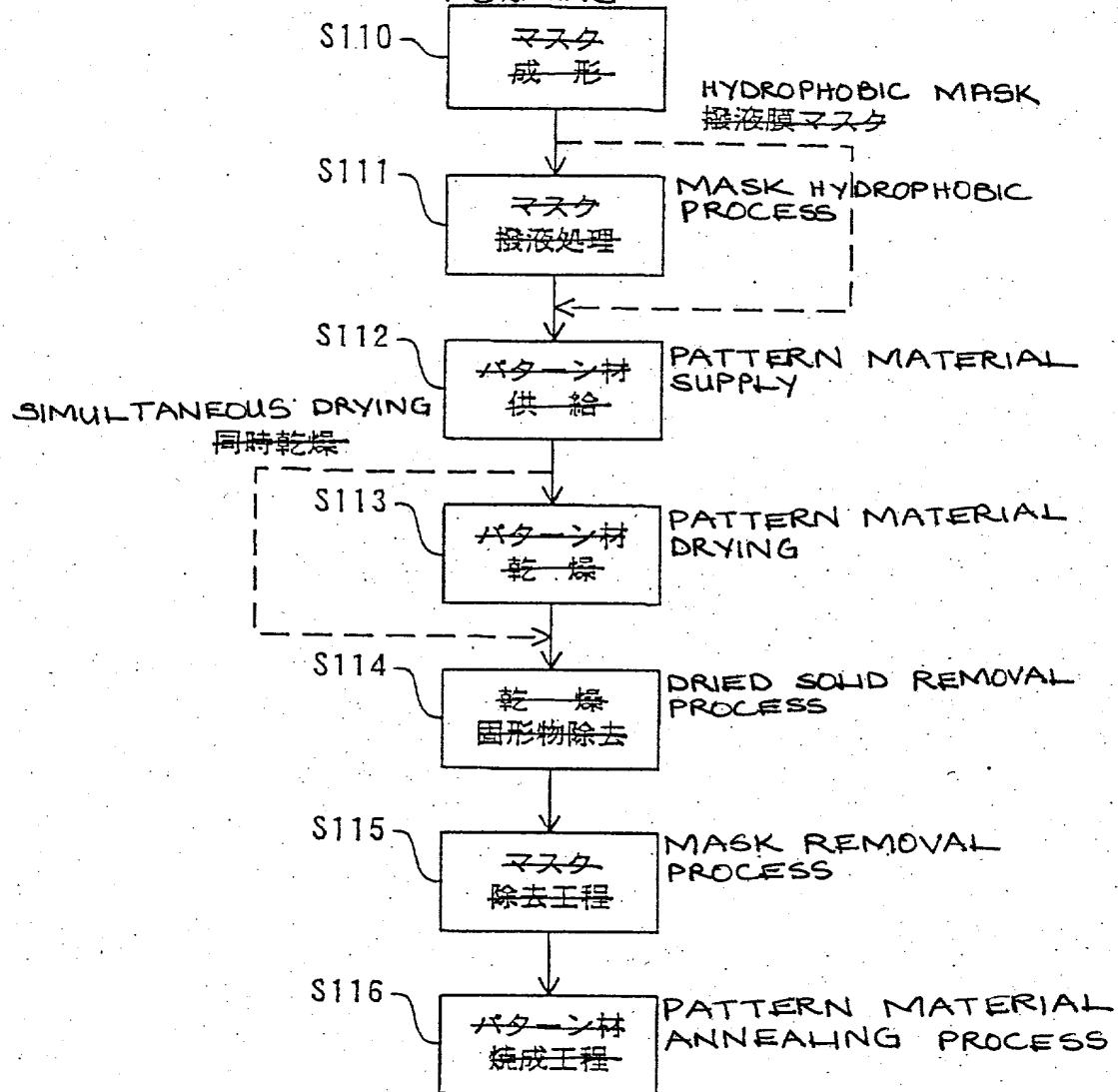
FIG.
8MASK
FORMING

FIG.

図 9

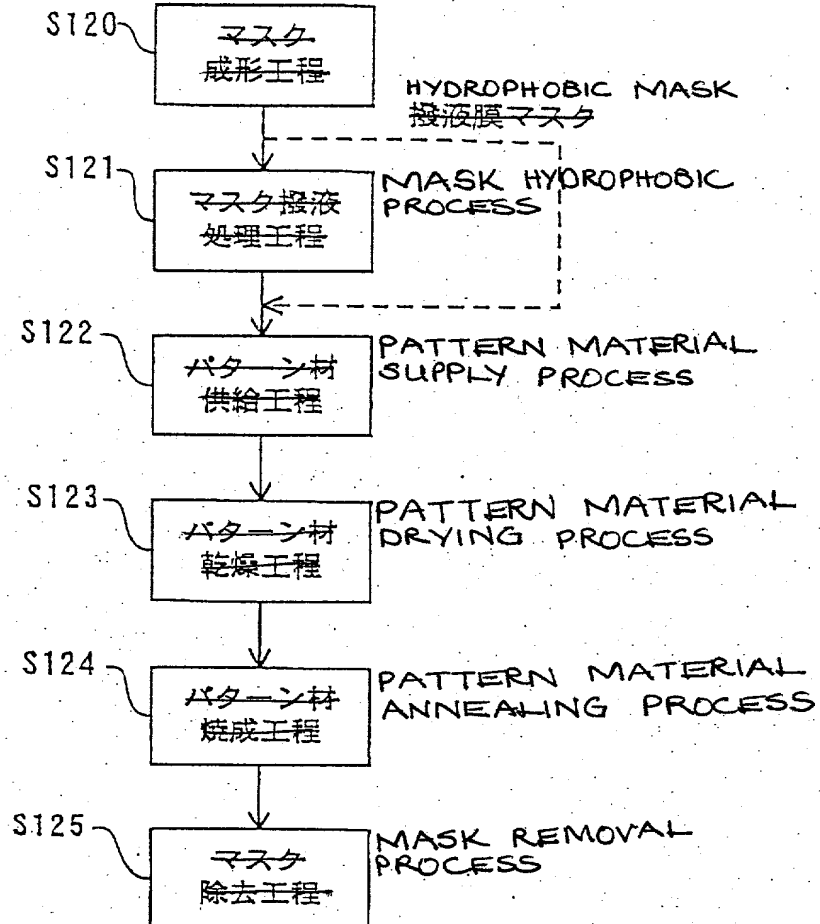
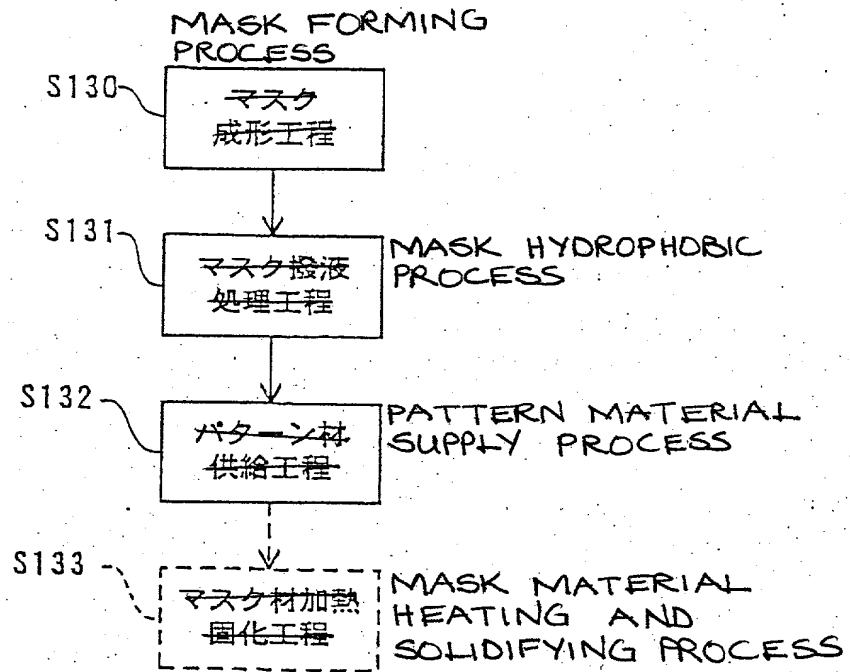
MASK FORMING
PROCESS

FIG.
図 10

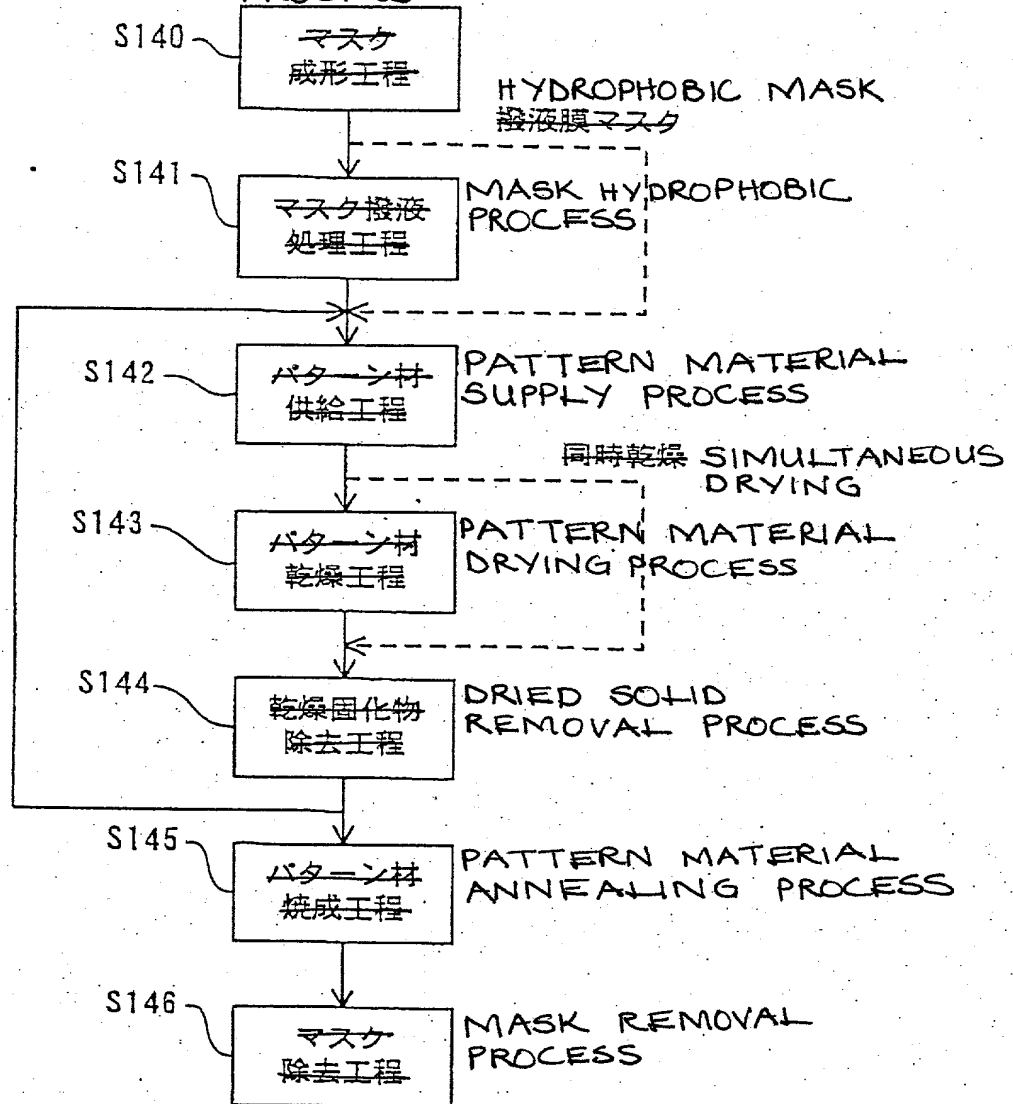
MASK FORMING
PROCESS

FIG.
図 12
MASK FORMING
PROCESS

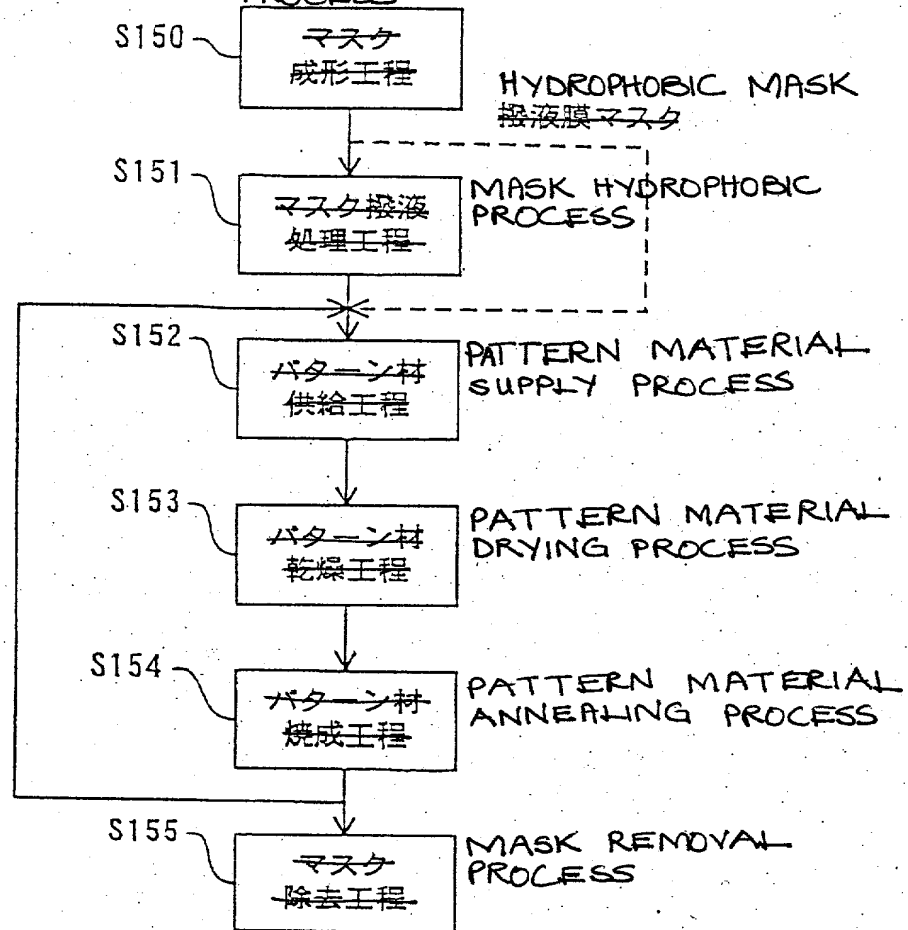


FIG.
図 13
WORK PIECE HYDROPHOBIC
PROCESS

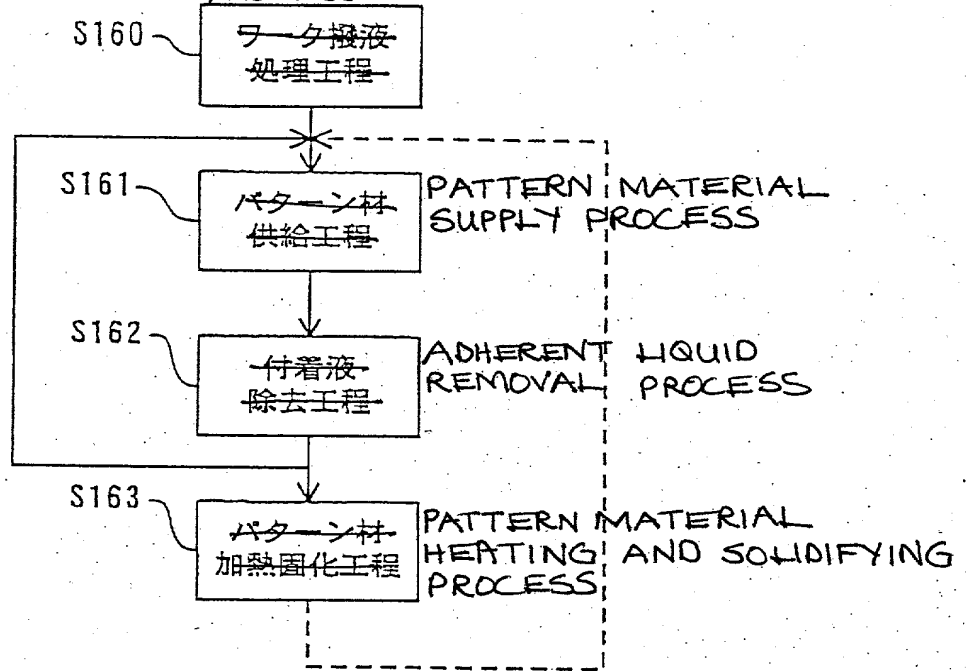


FIG.
14
WORKPIECE HYDROPHOBIC
PROCESS

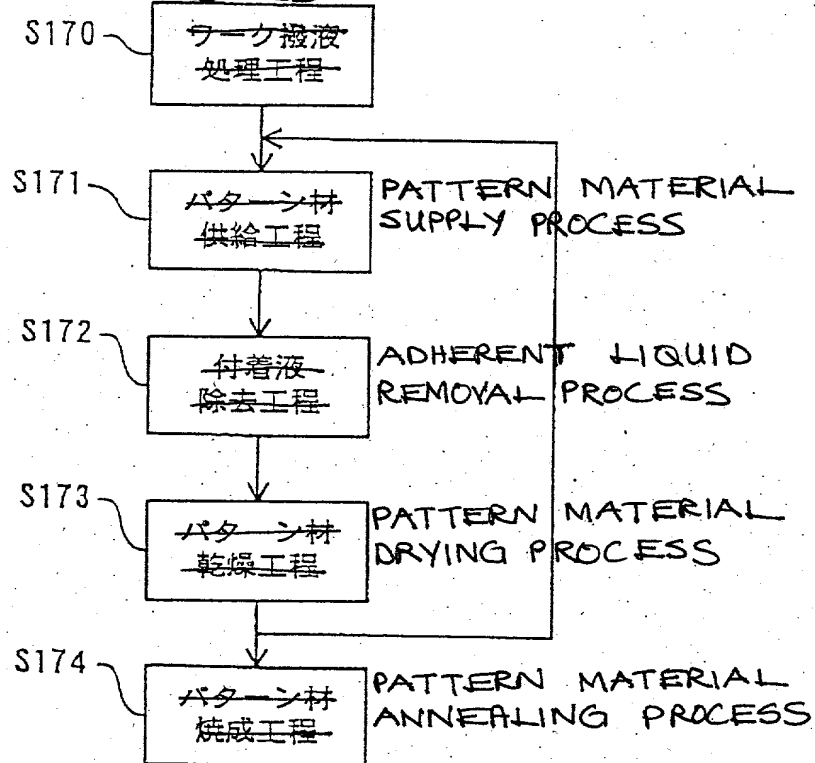


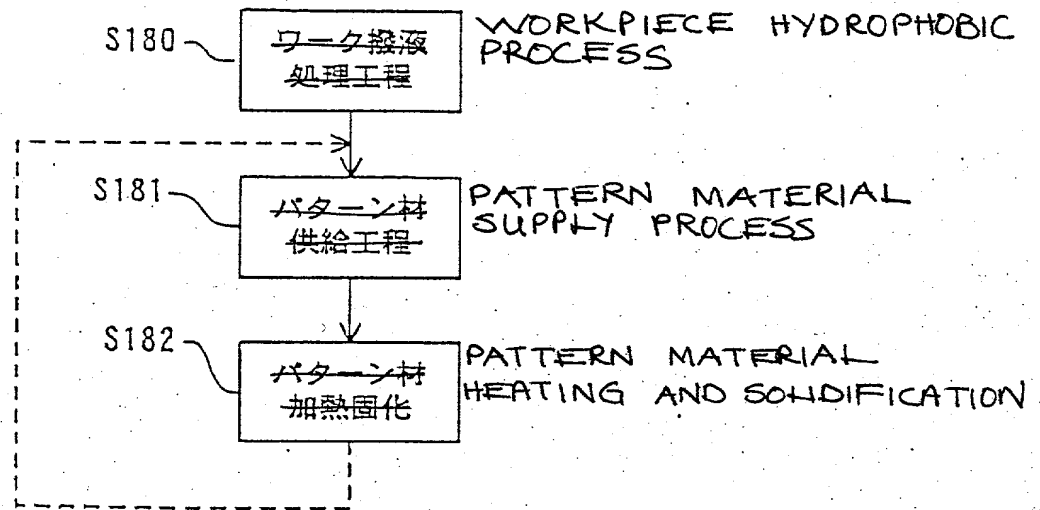
FIG.
図 15

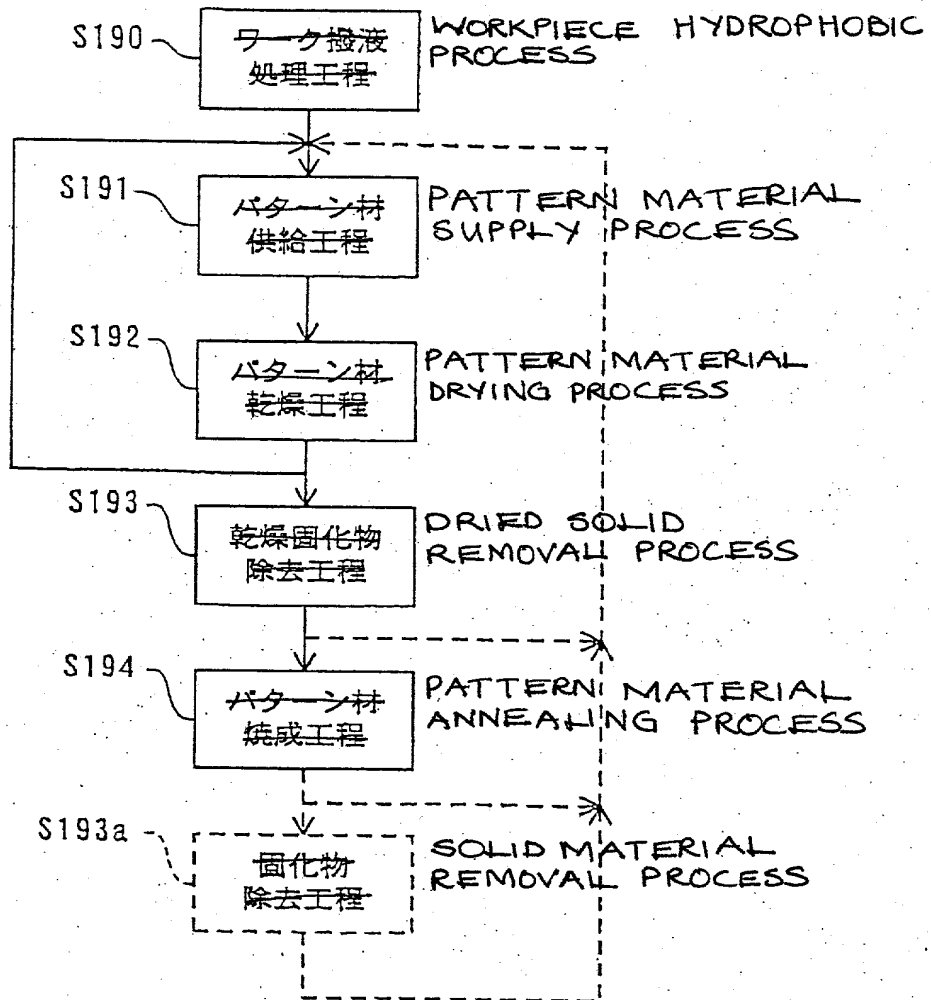
FIG.
図 16

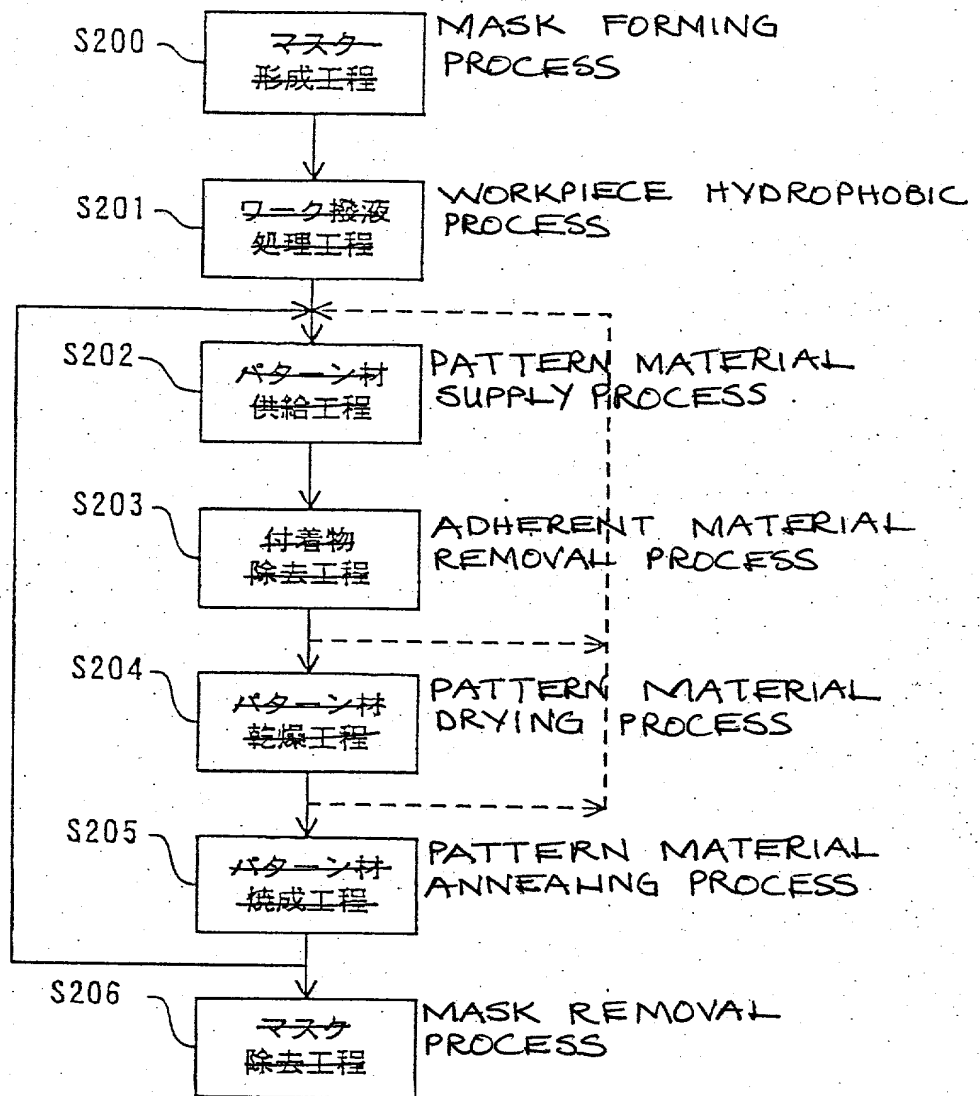

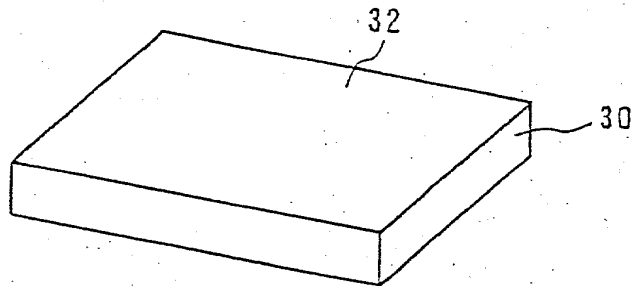
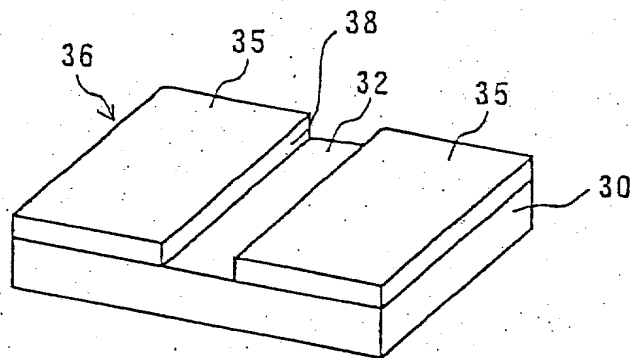
FIG.
図 17

FIG.
 18

(1)



(2)



(3)

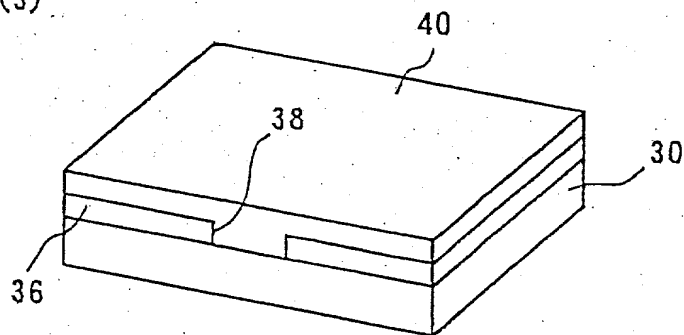
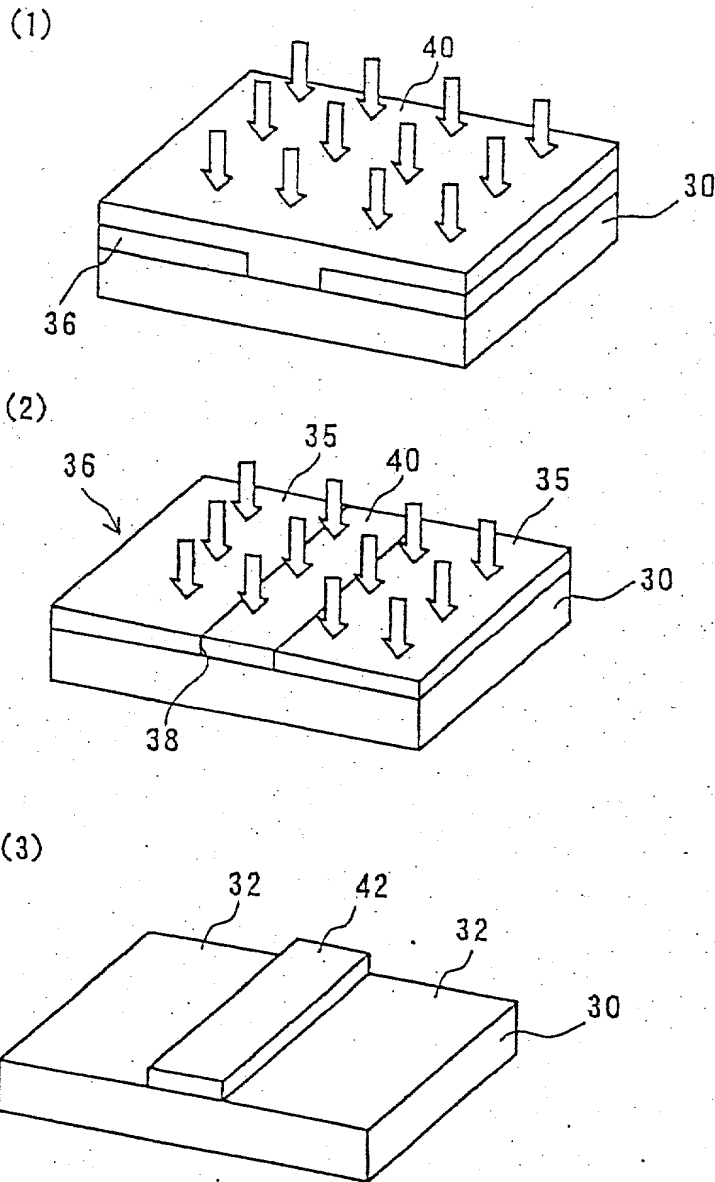
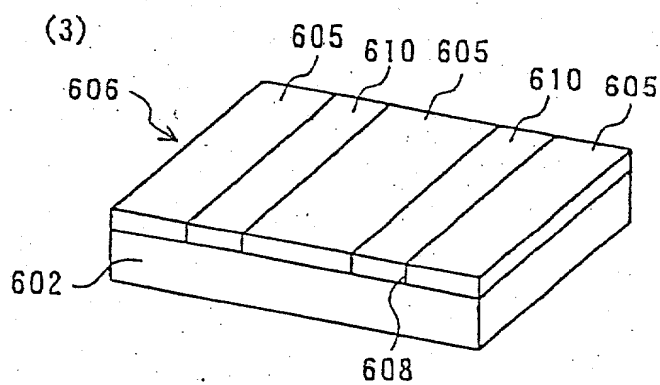
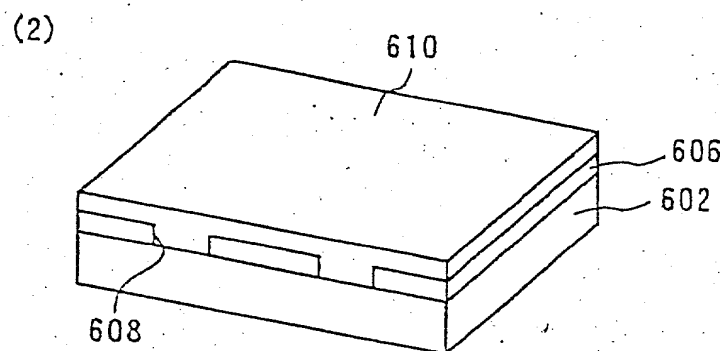
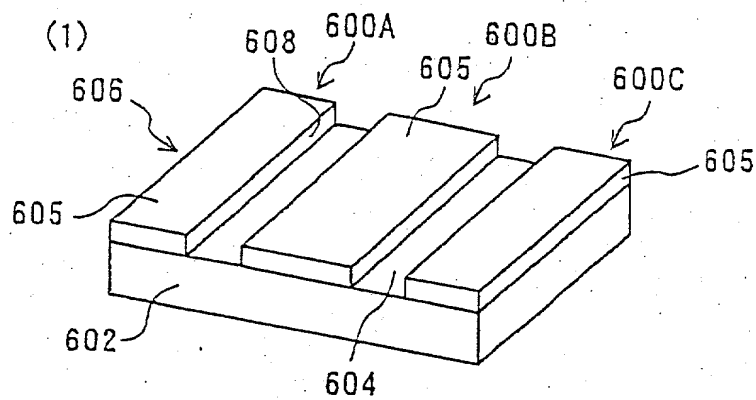


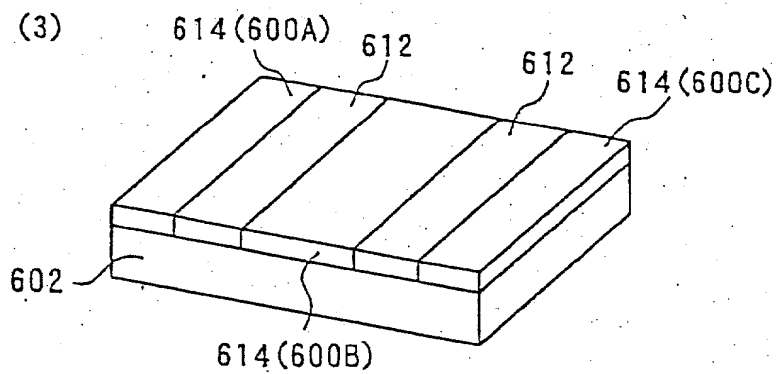
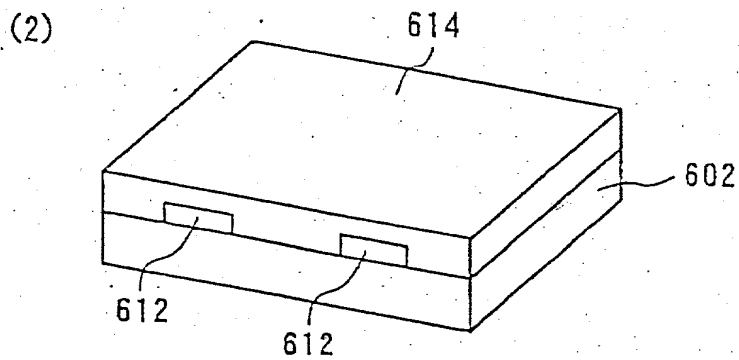
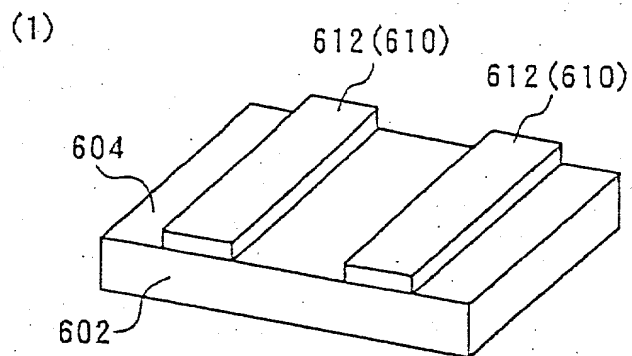
FIG.
19



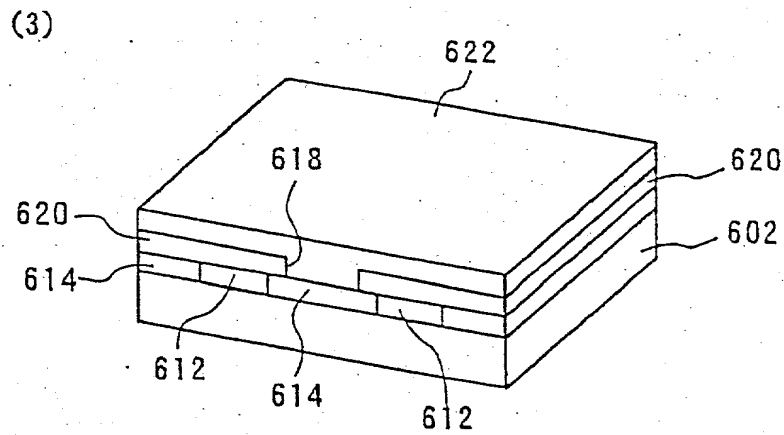
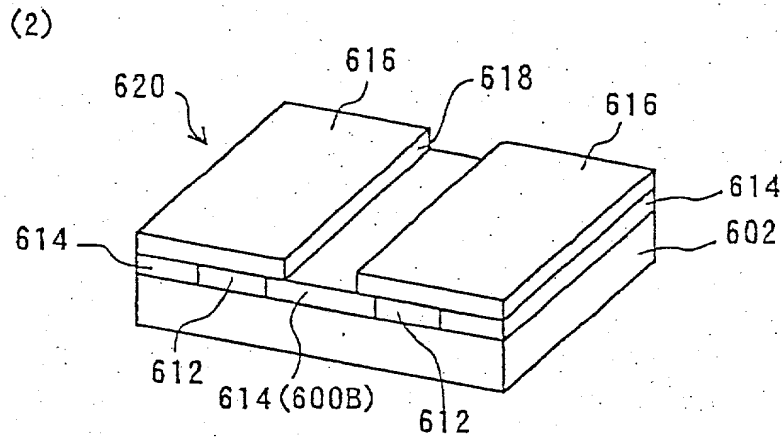
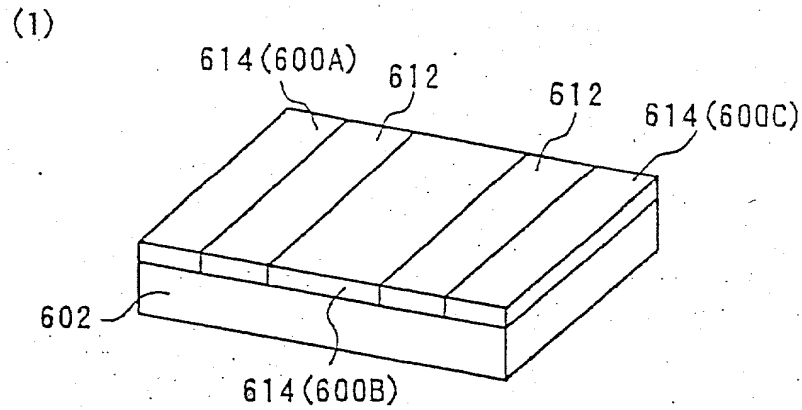
20/33
FIG.
20



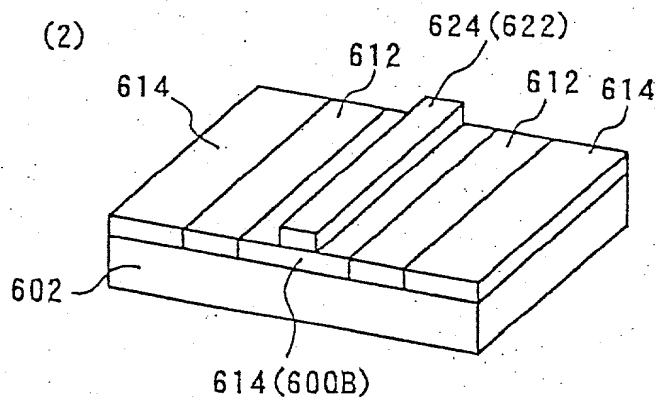
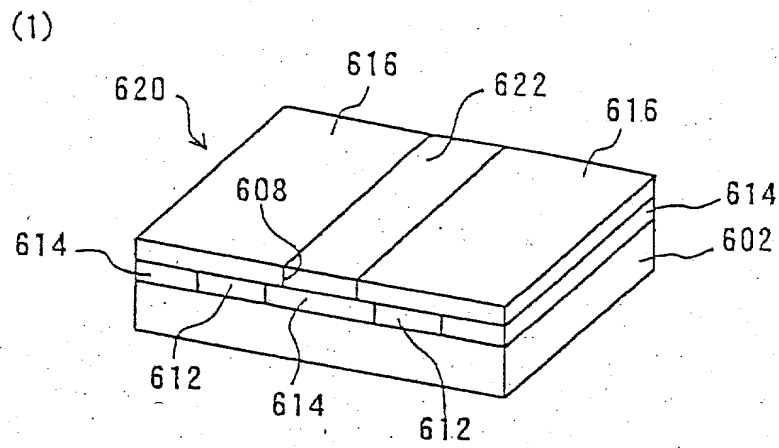
21/33
FIG.
~~21~~ 21



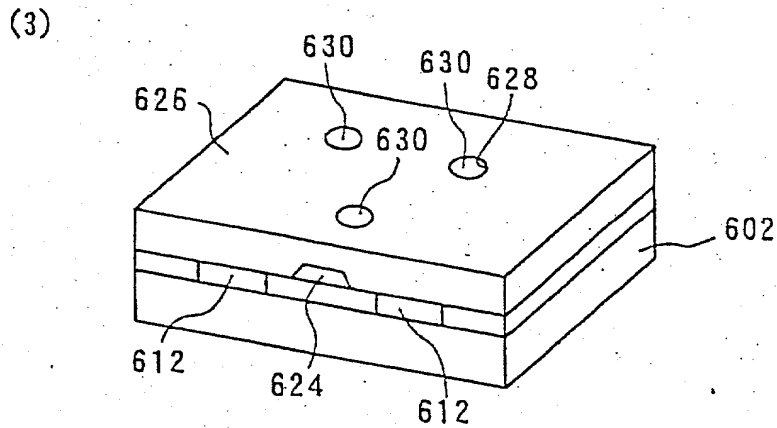
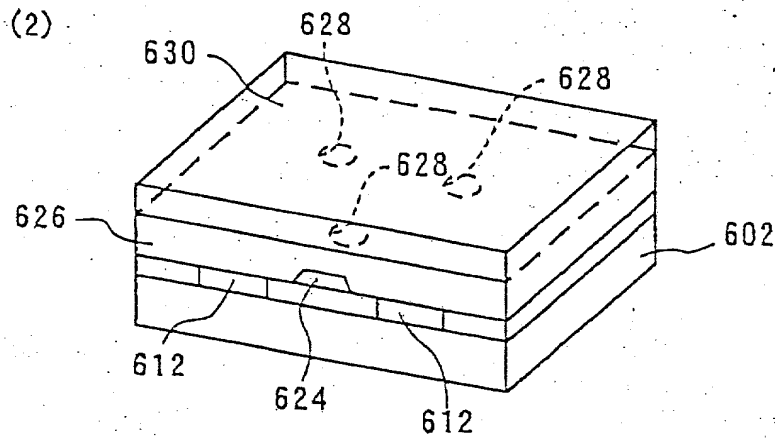
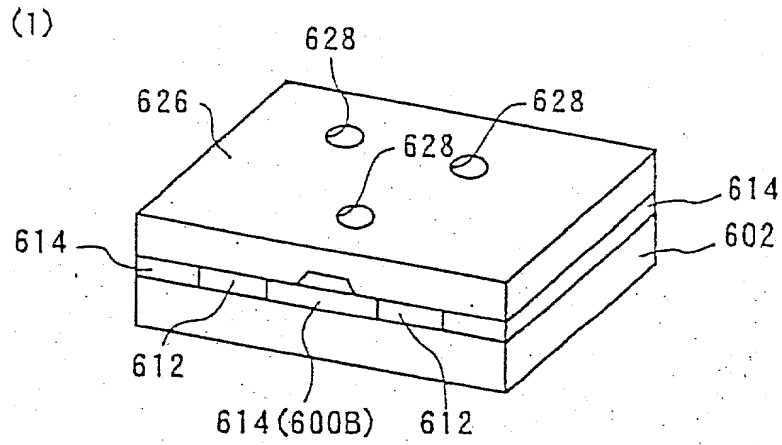
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FIG.
22



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FIG.
23

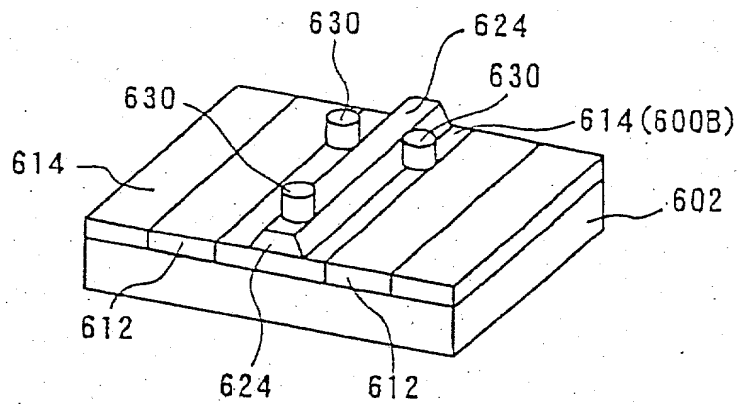


24/33
FIG.
~~24~~ 24

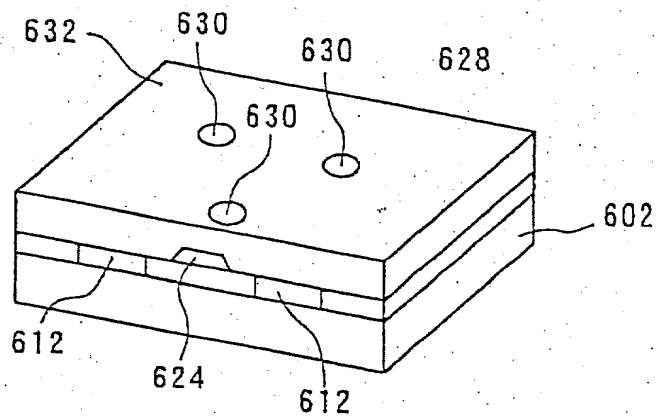


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FIG.
25

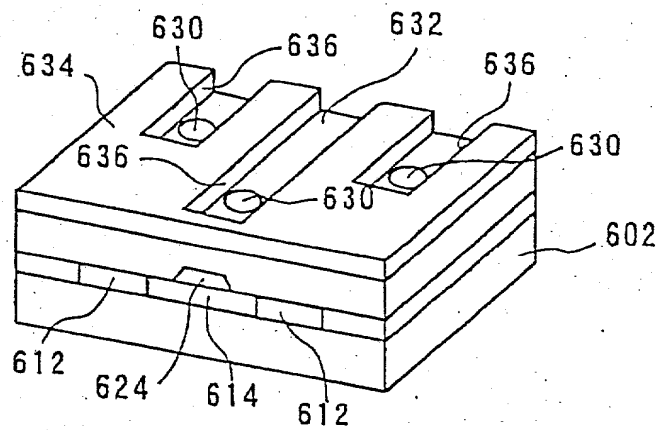
(1)



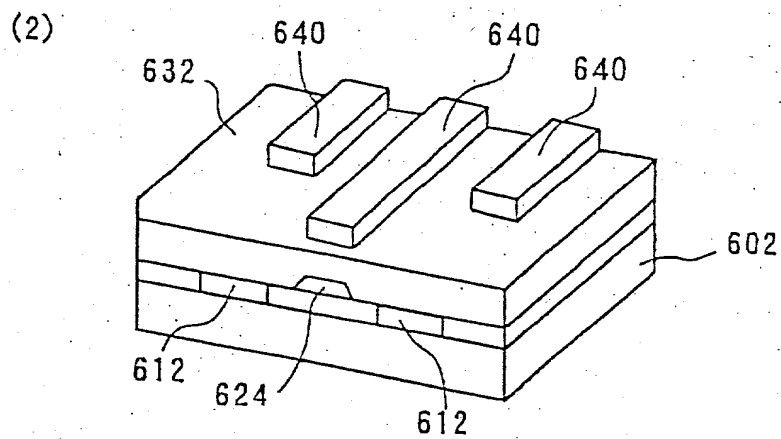
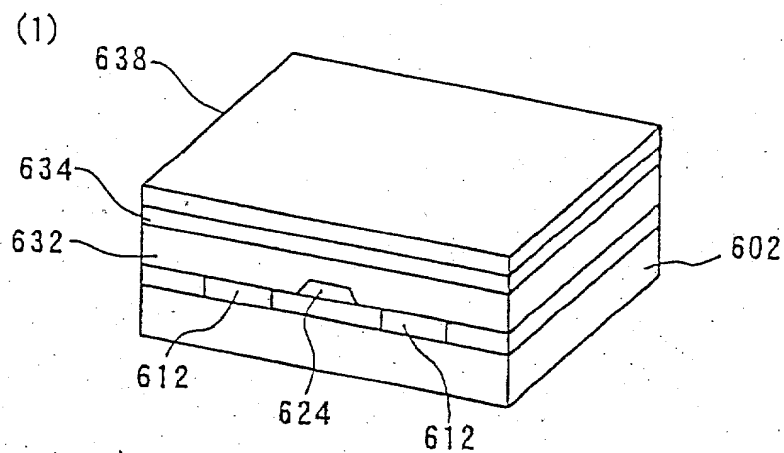
(2)



(3)

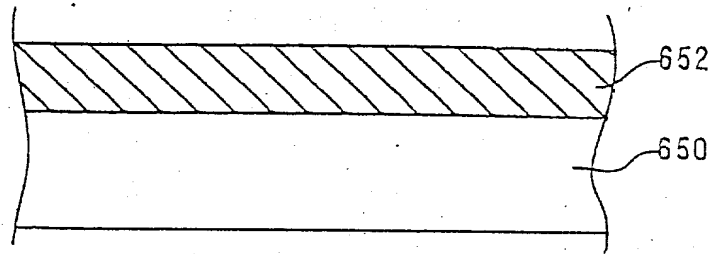


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FIG.
~~25~~ 26

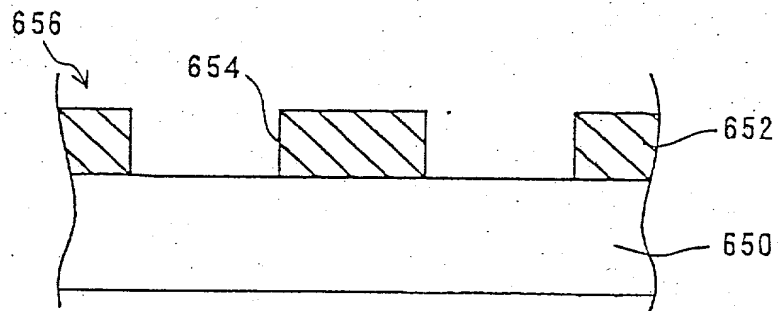


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FIG.
27

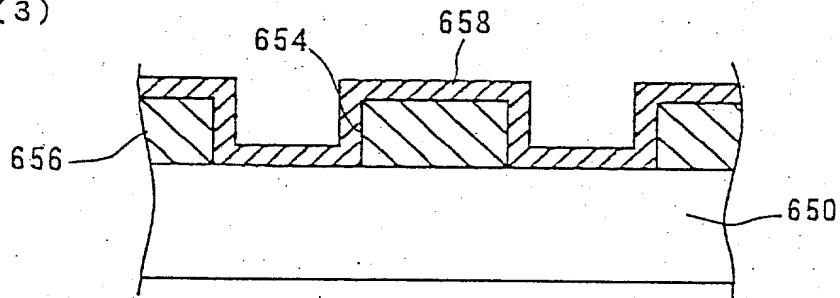
(1)



(2)



(3)



(4)

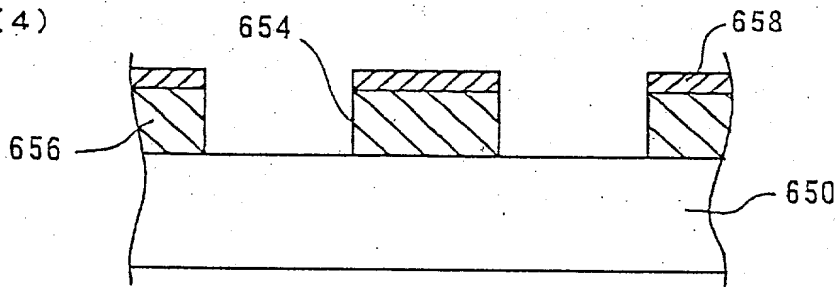


FIG.
28

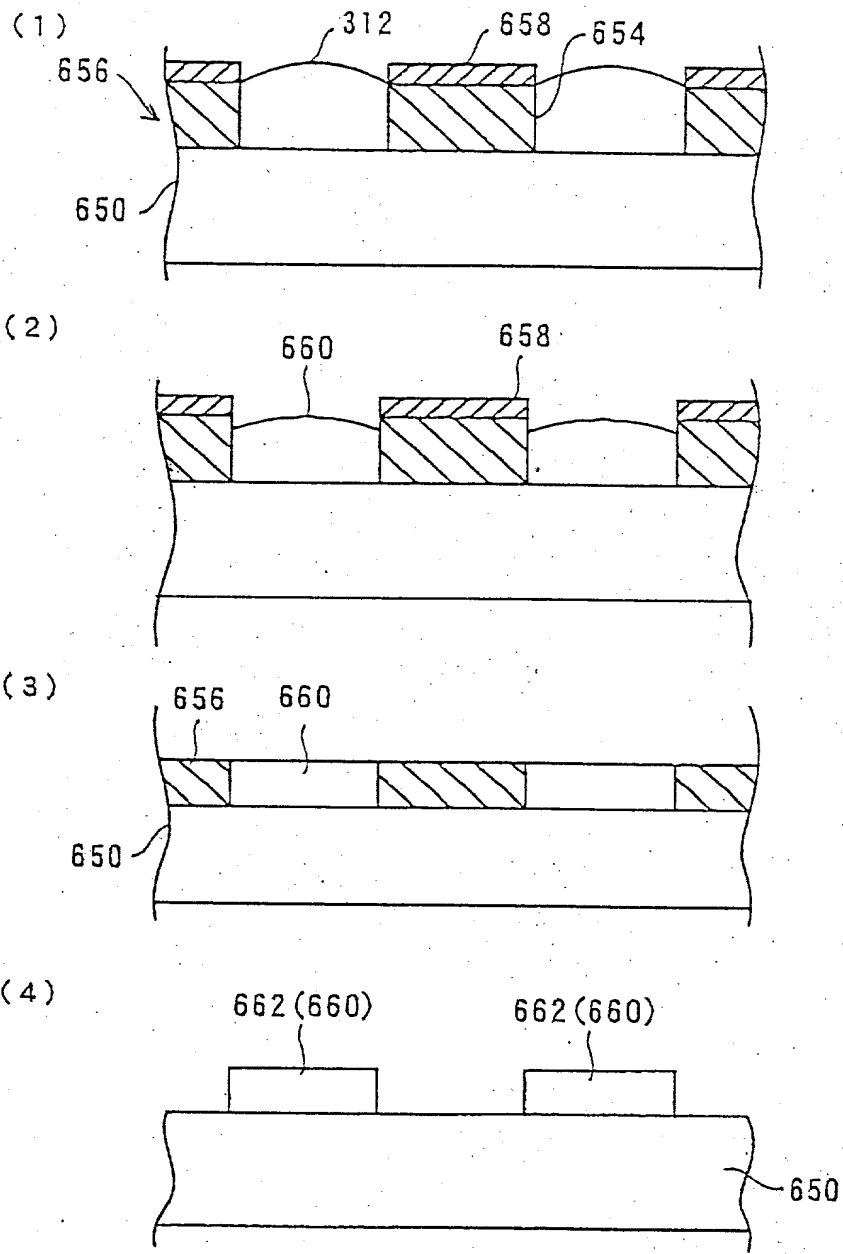


FIG.
29

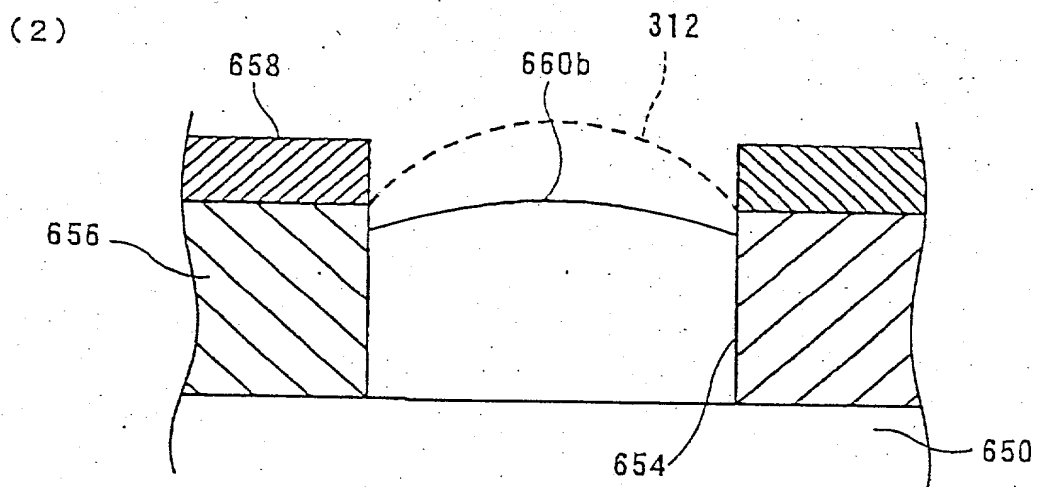
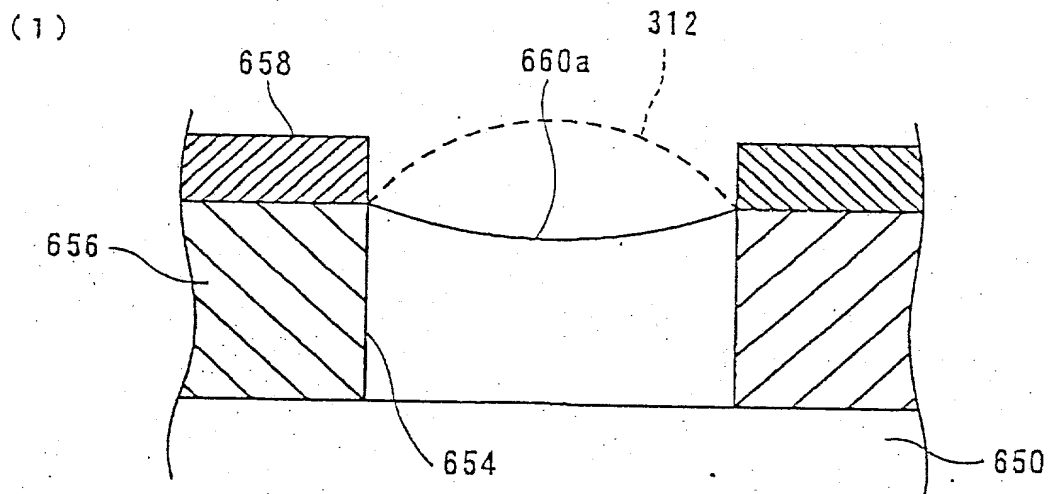


FIG.
30

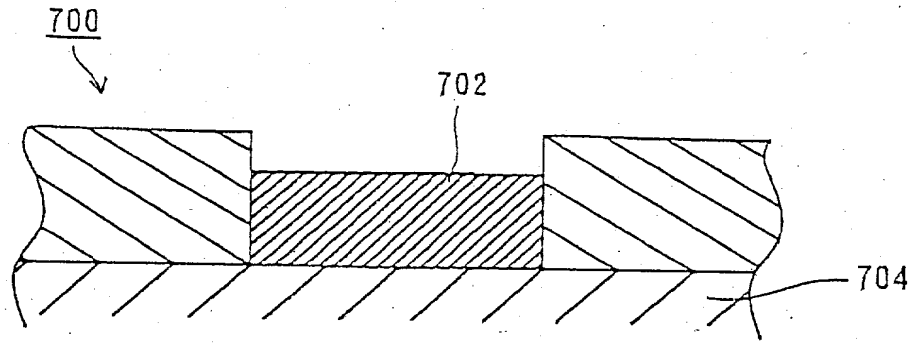


FIG.
31

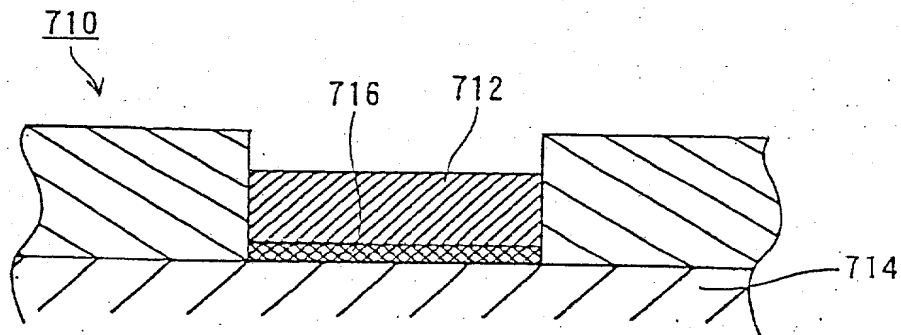


FIG.
~~31~~ 32

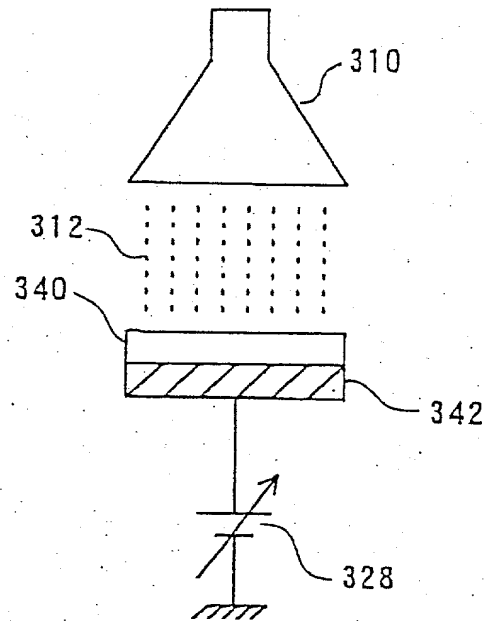
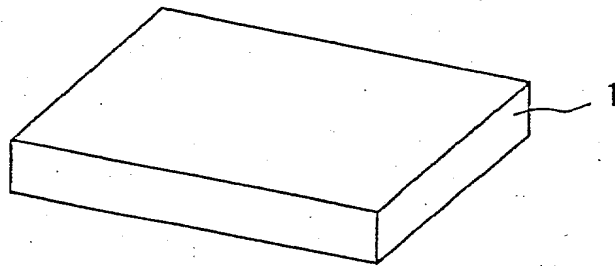
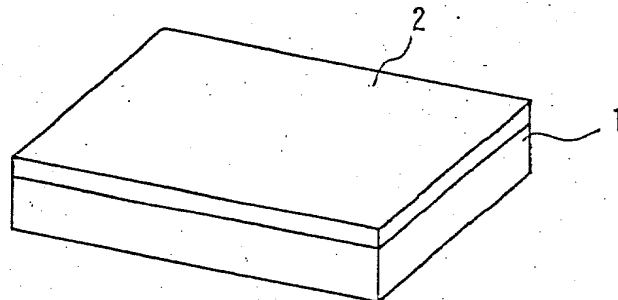


FIG.
~~32~~ 33

(1)



(2)



(3)

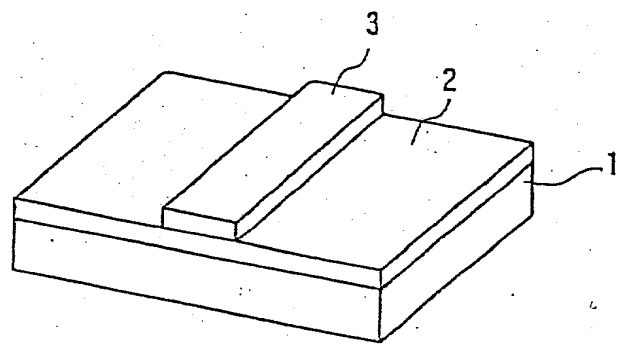


FIG.
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